

Fig. 2A

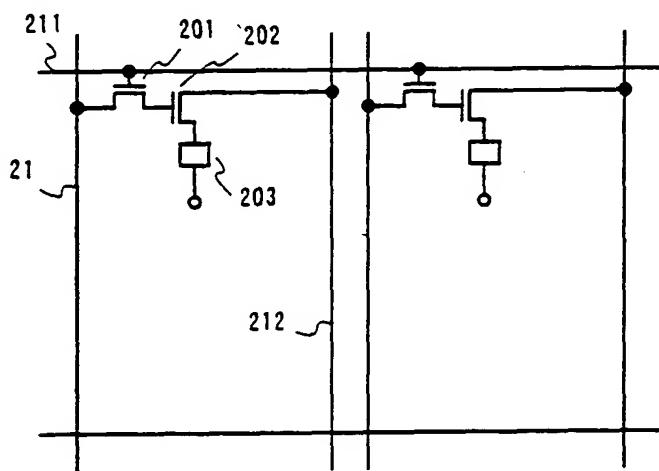
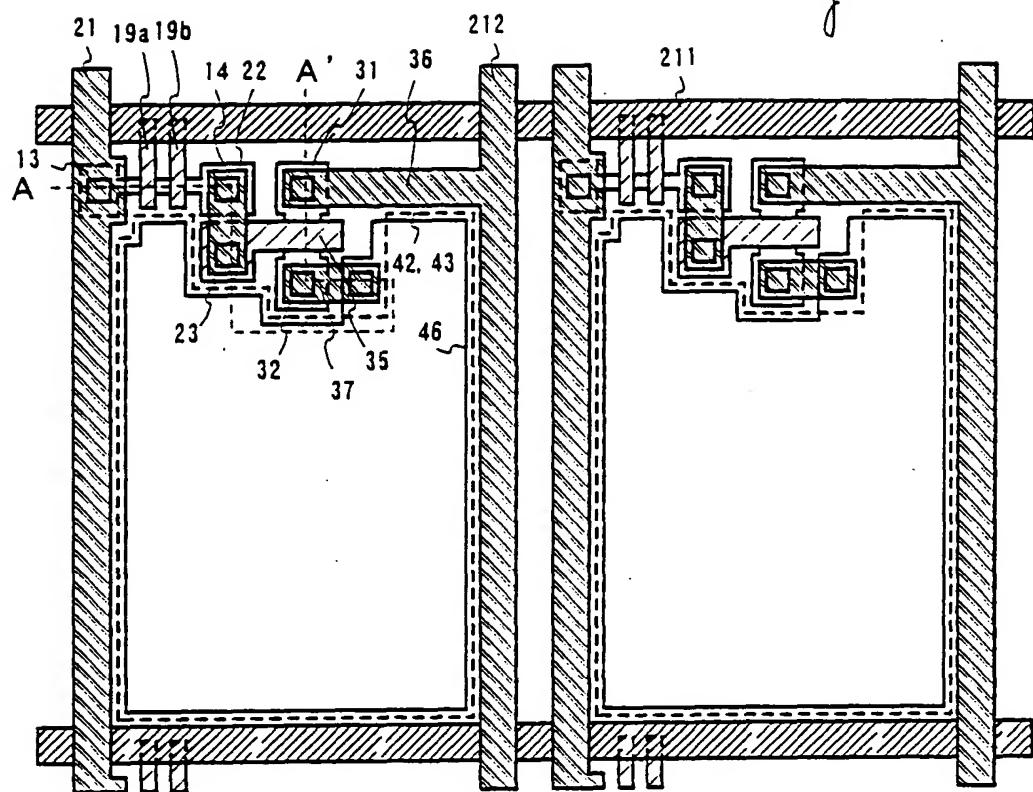


Fig. 2B

Fig. 3A CRYSTALLIZATION STEP

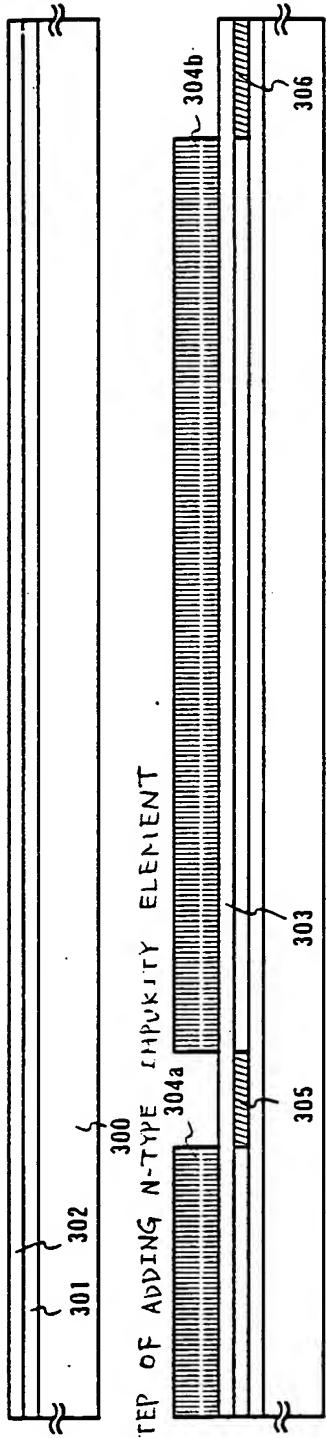


Fig. 3B STEP OF ADDING N-TYPE IMPURITY ELEMENT



Fig. 3C LASER ANNEALING STEP



Fig. 3D

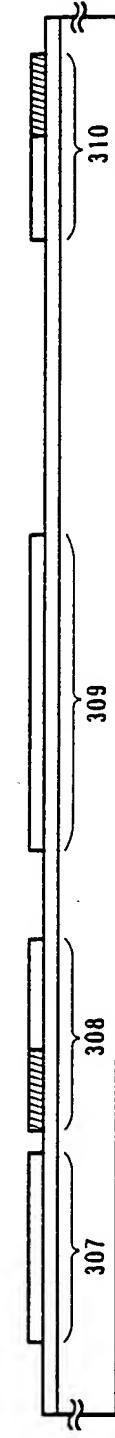
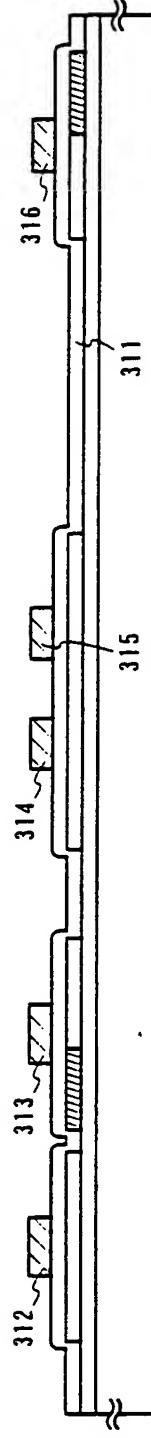


Fig. 3E



STEP OF ADDING N-TYPE IMPURITY ELEMENT

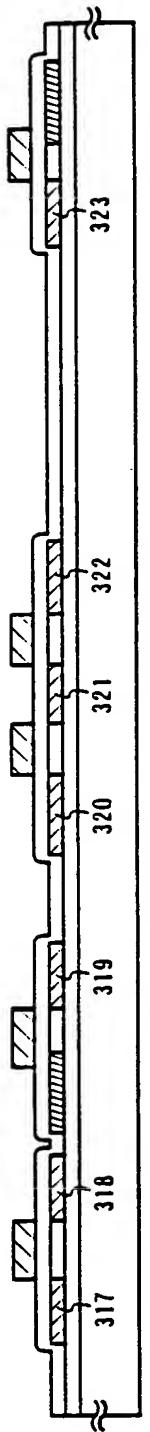


Fig. 4A

STEP OF ADDING N-TYPE IMPURITY ELEMENT

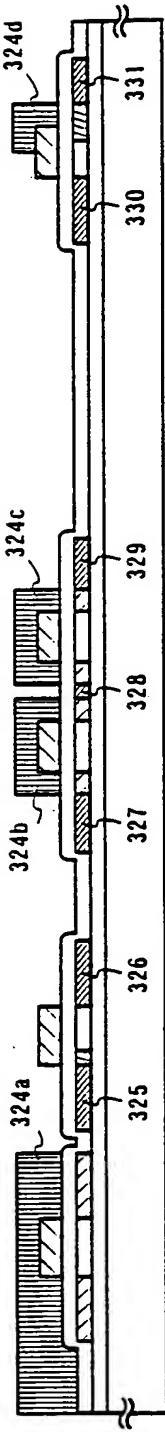


Fig. 4B

STEP OF ADDING P-TYPE IMPURITY ELEMENT

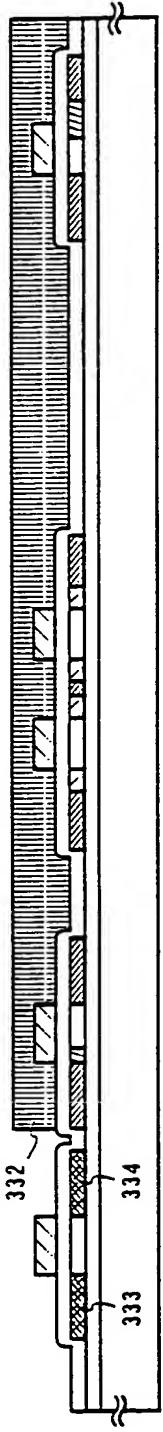


Fig. 4C

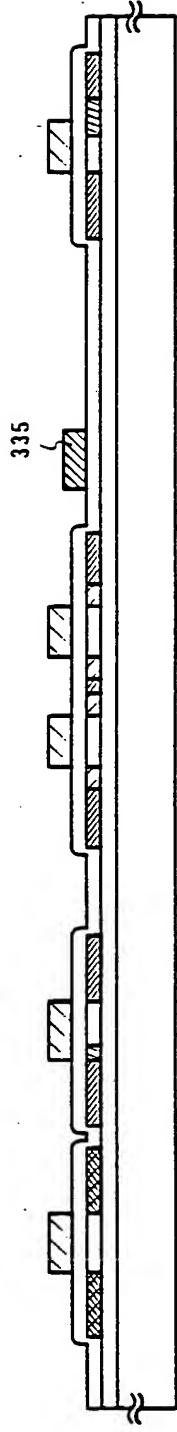
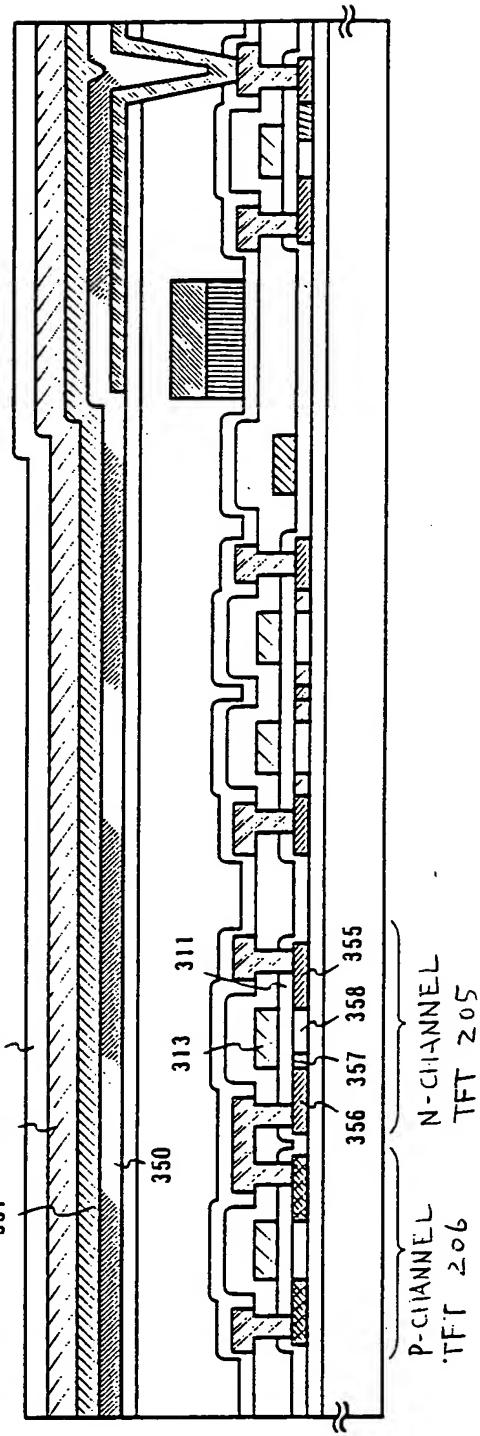
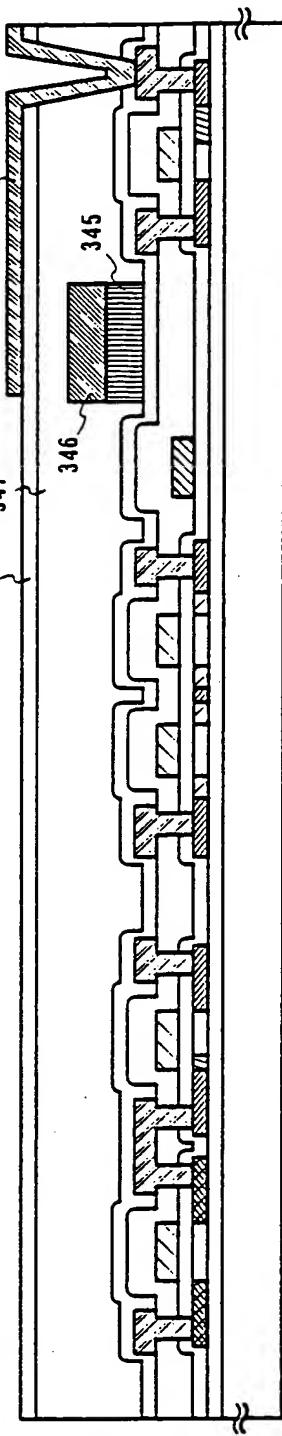
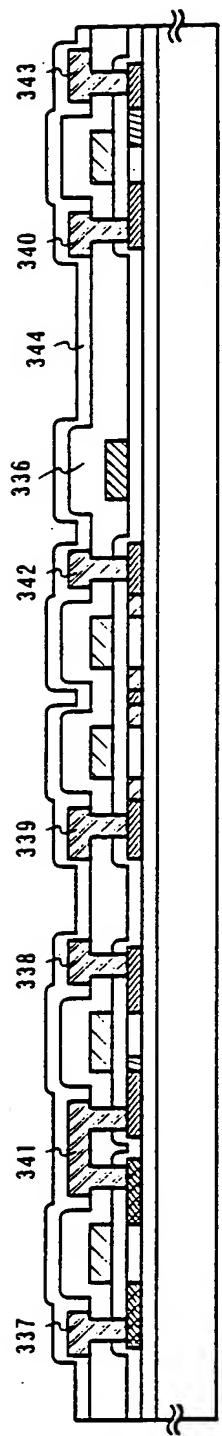


Fig. 4D



P-CHANNEL  
TFT 206

N-CHANNEL  
TFT 205

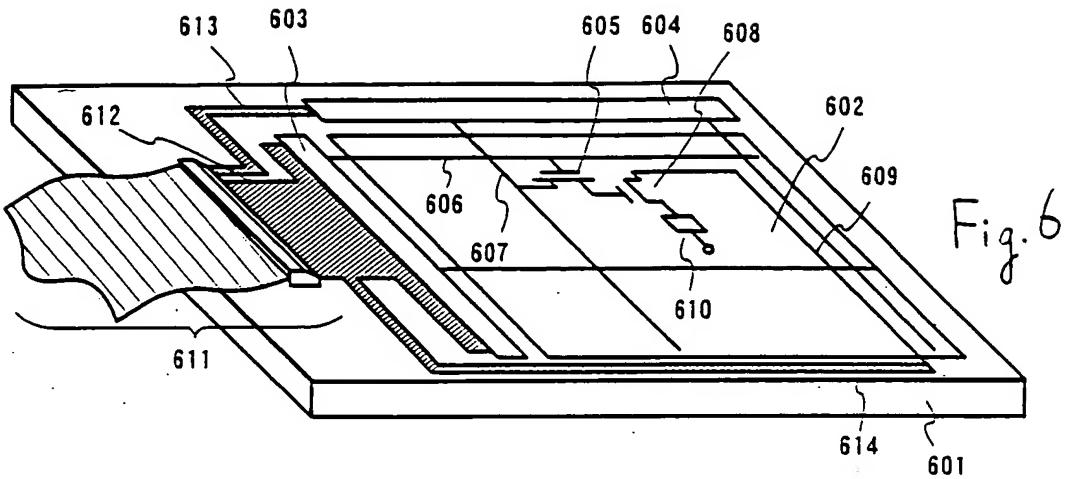


Fig. 6

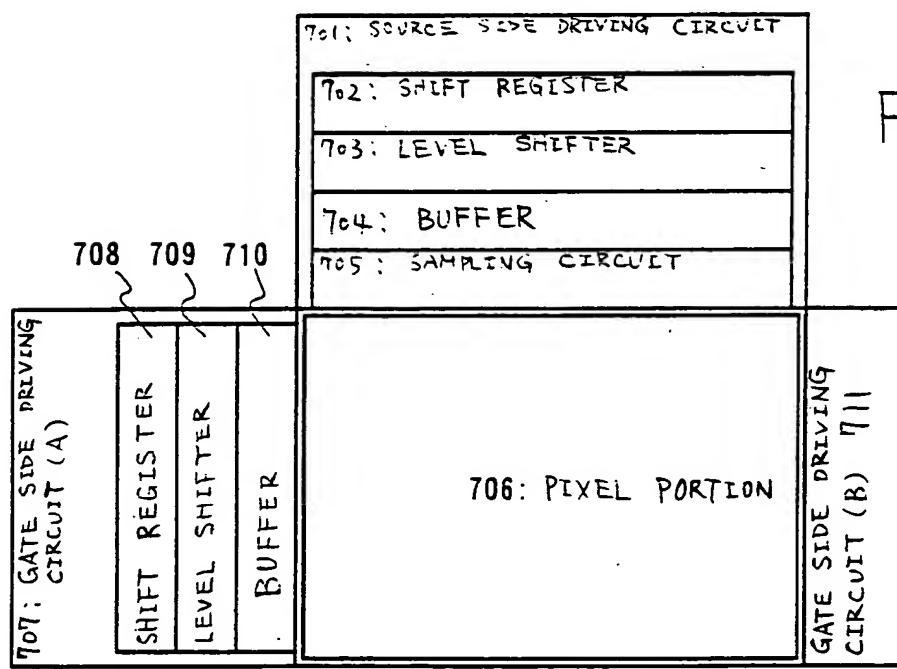
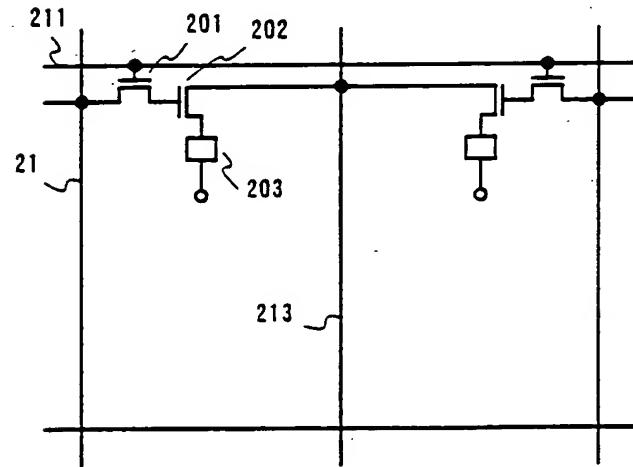
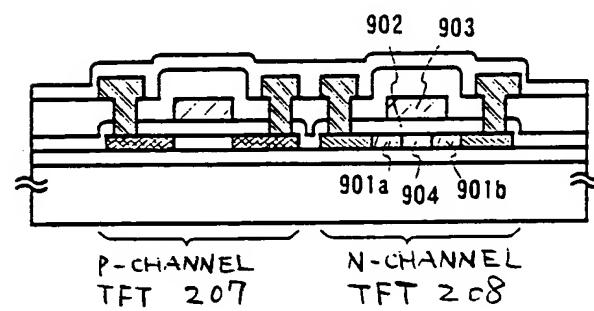
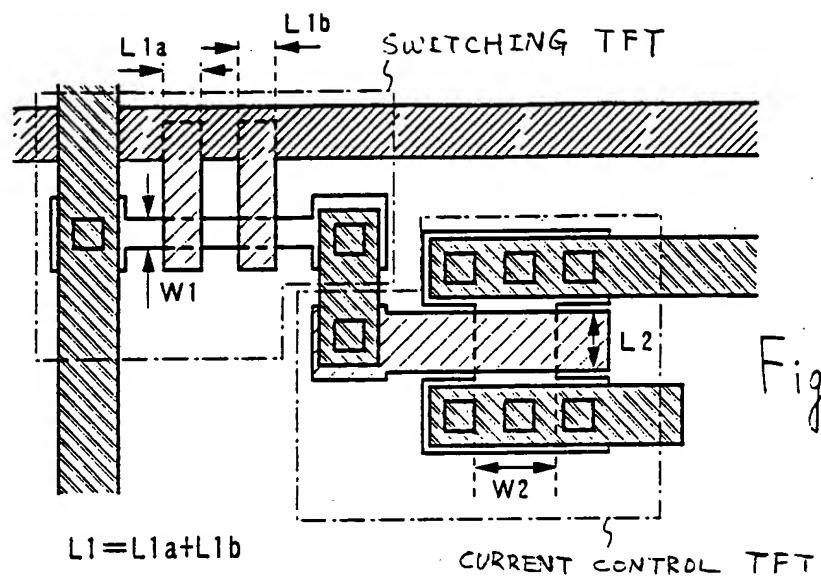


Fig. 7



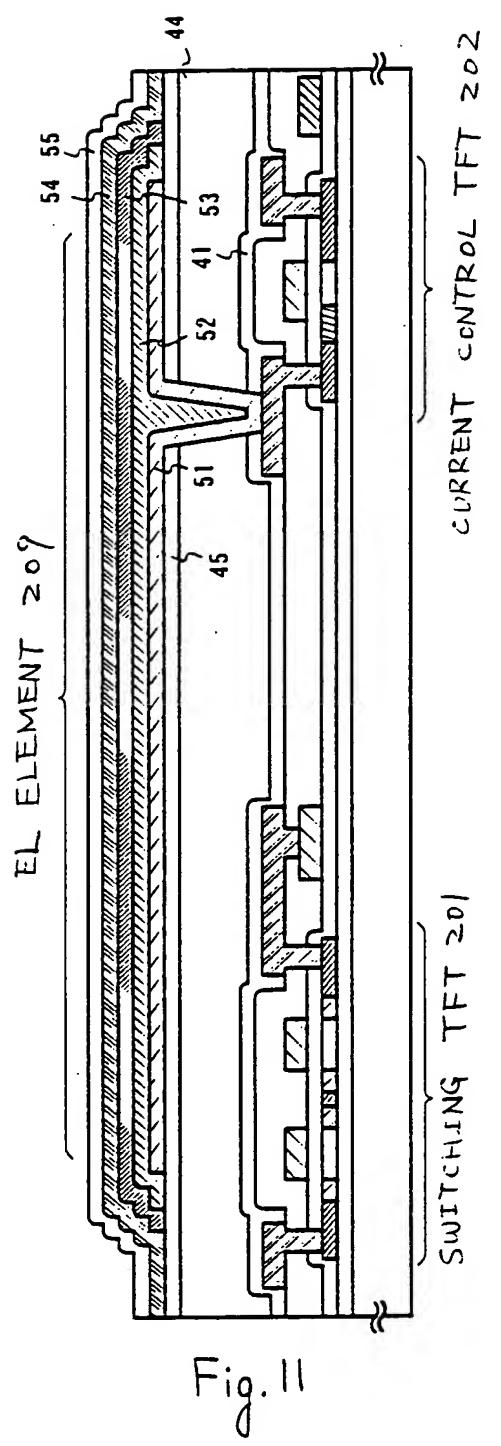


Fig. 11

Fig. 12A

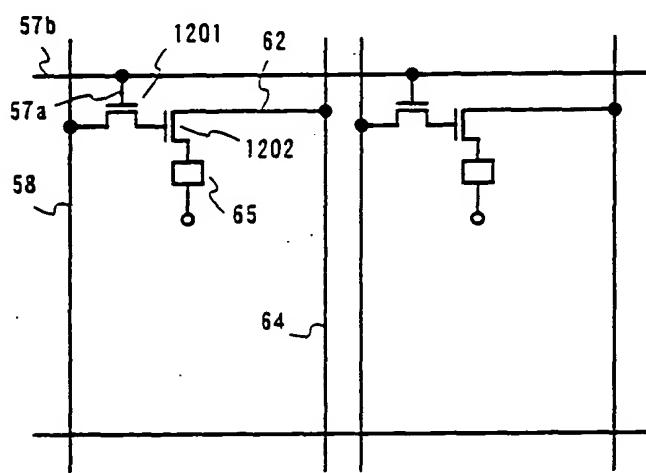
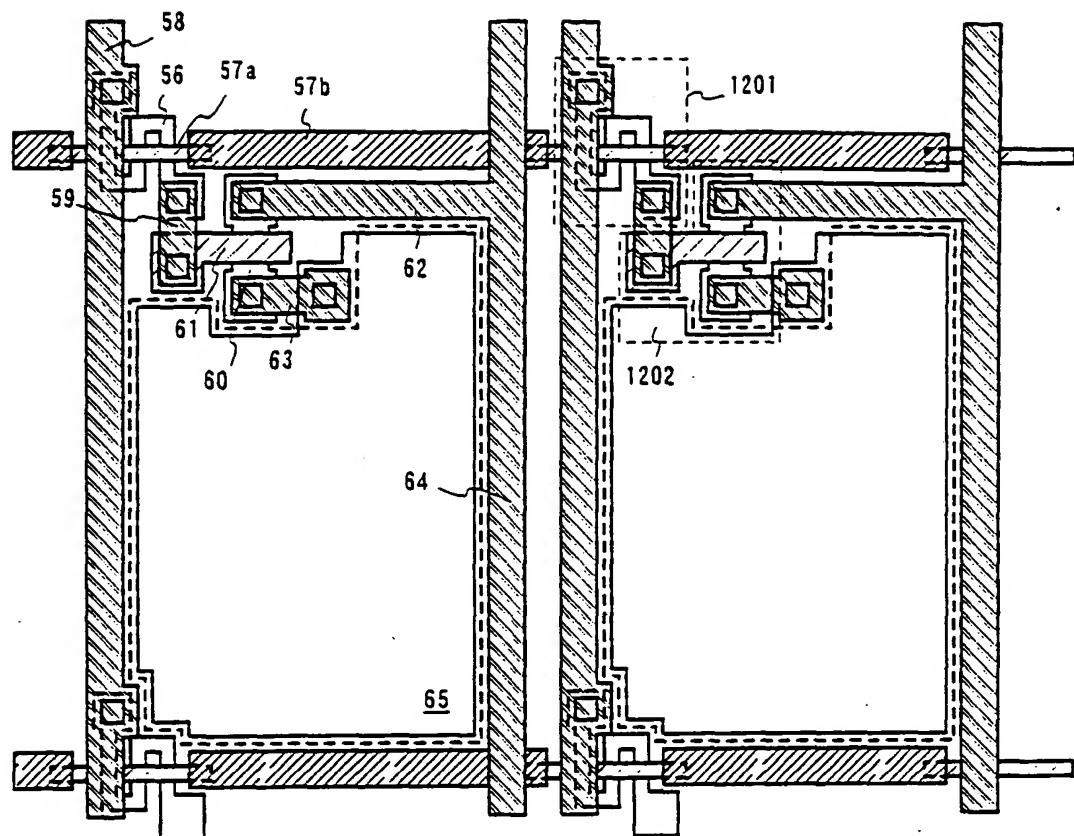
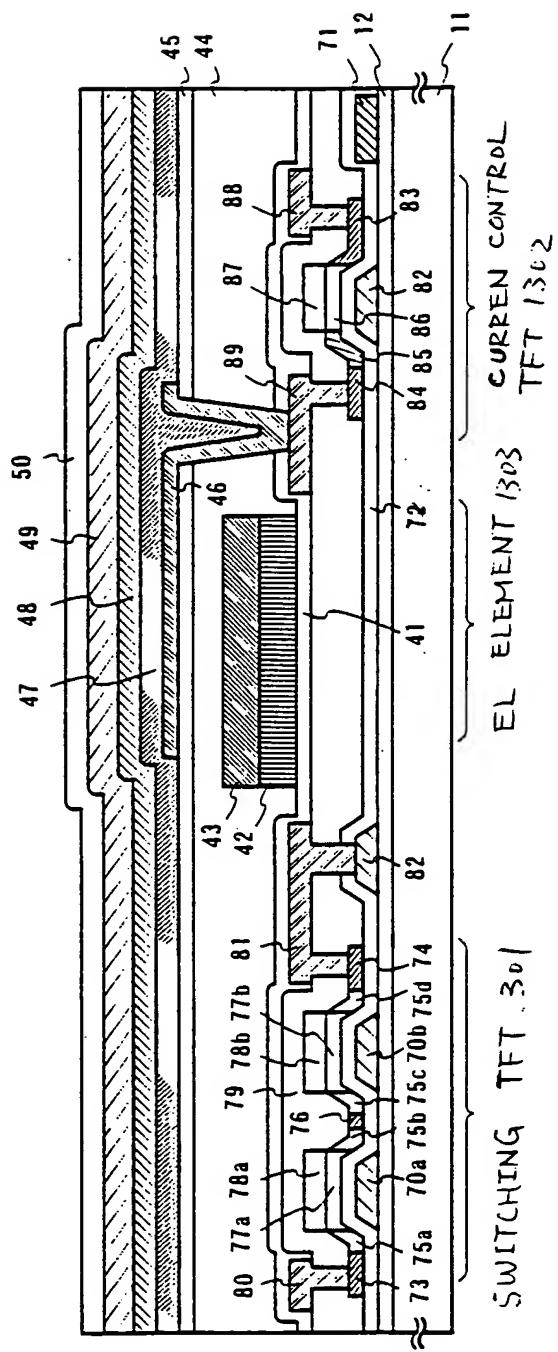


Fig. 12B



$T_{i\alpha}$

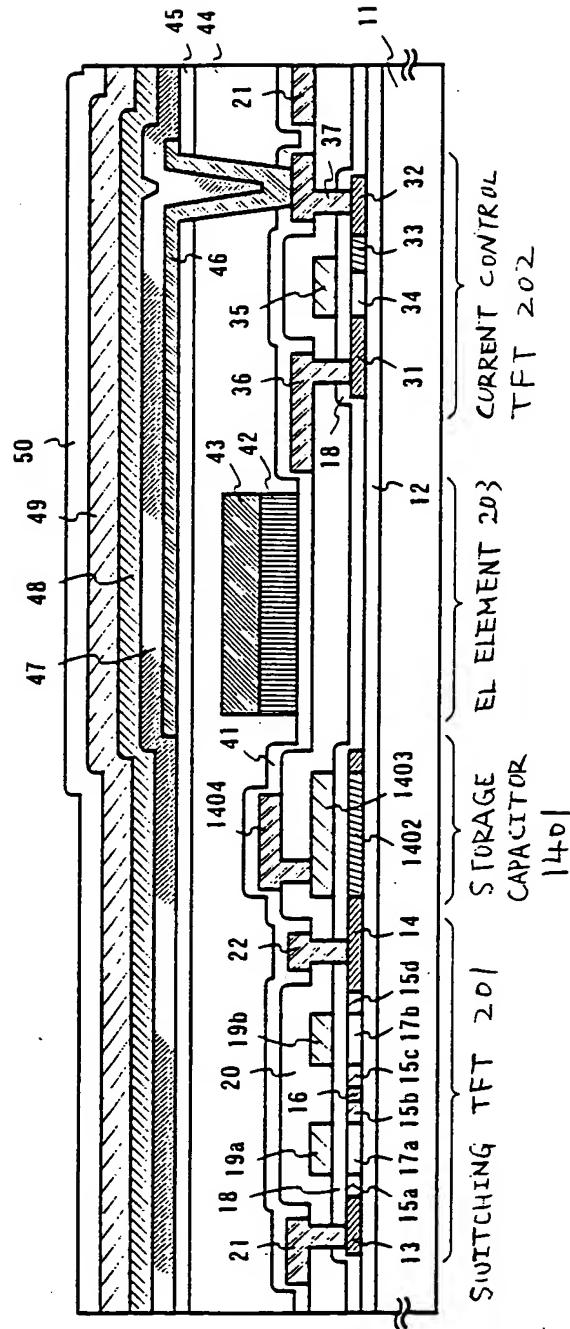


Fig. 14

Fig. 15A

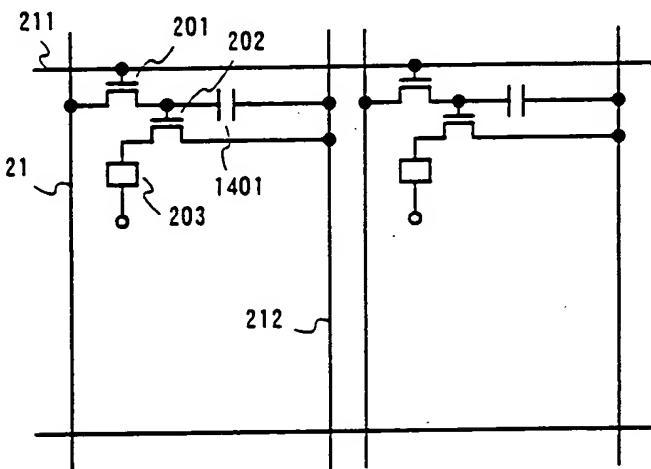
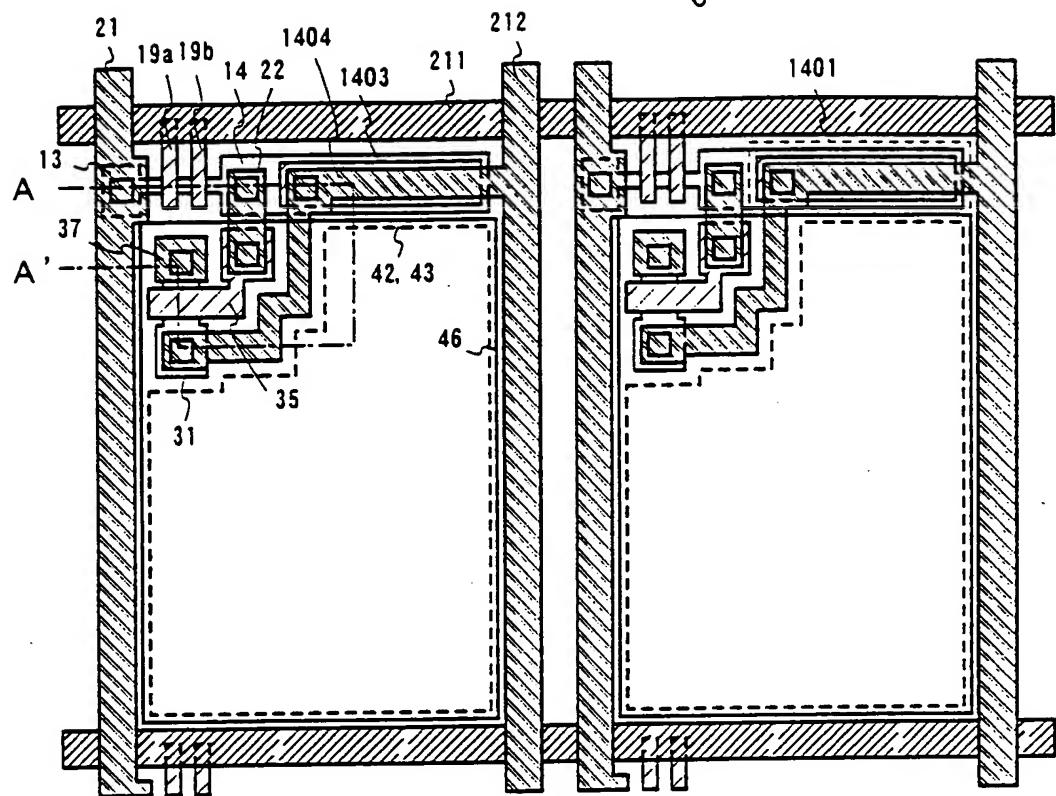
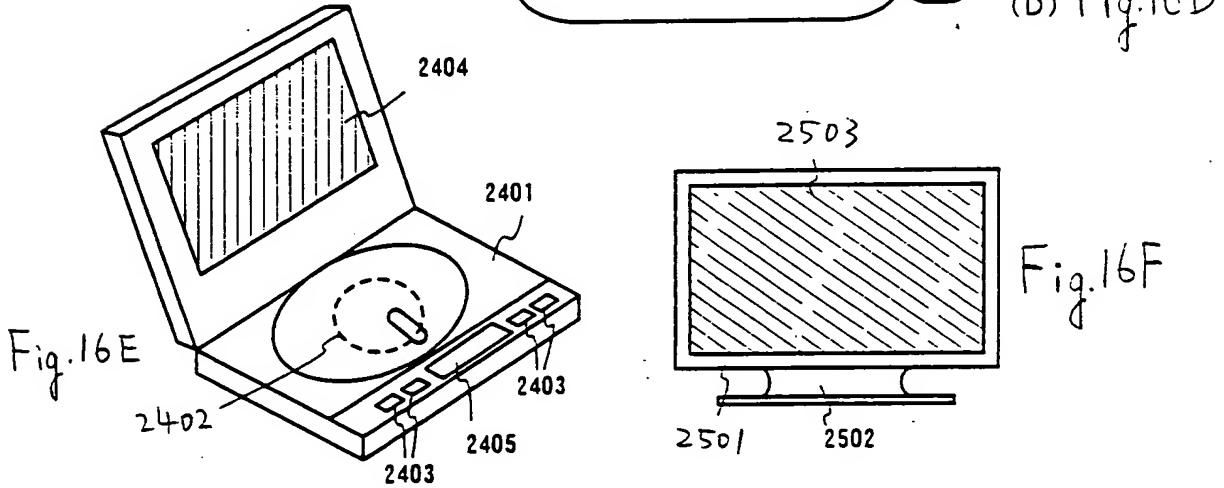
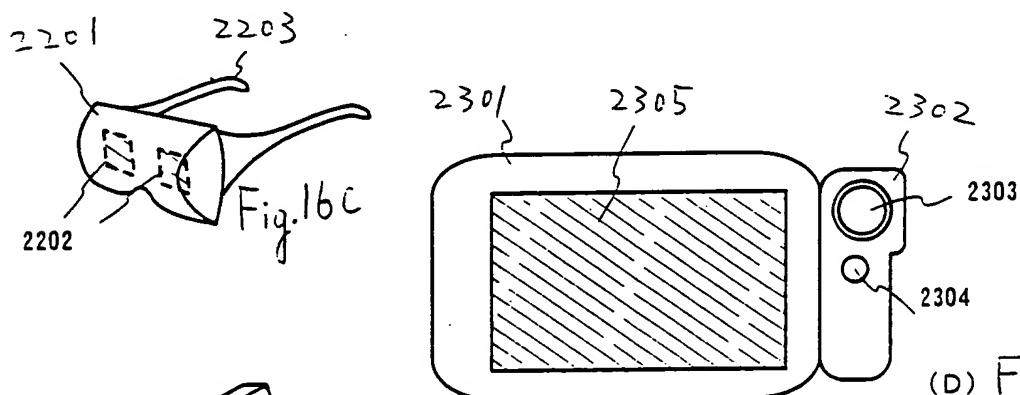
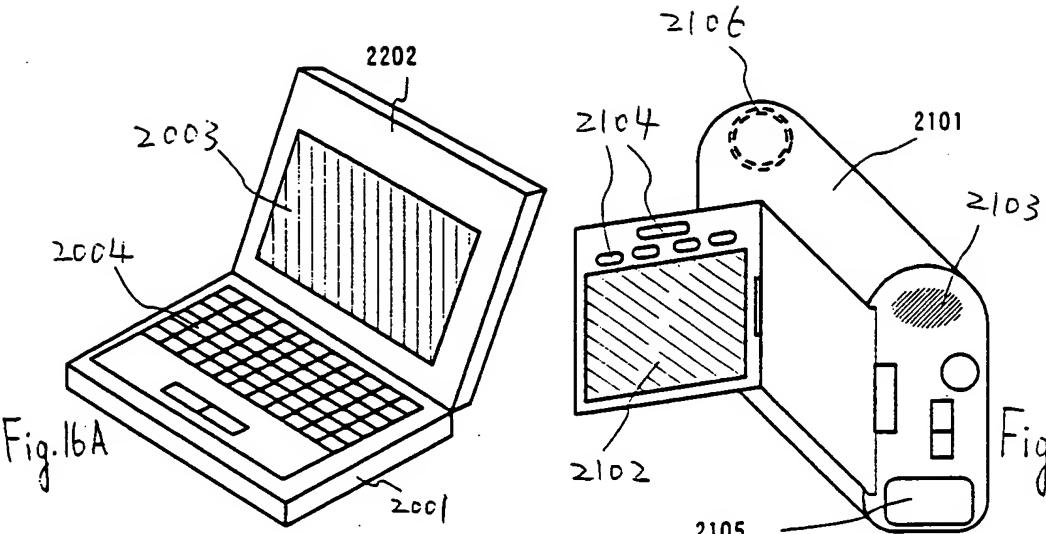


Fig. 15B



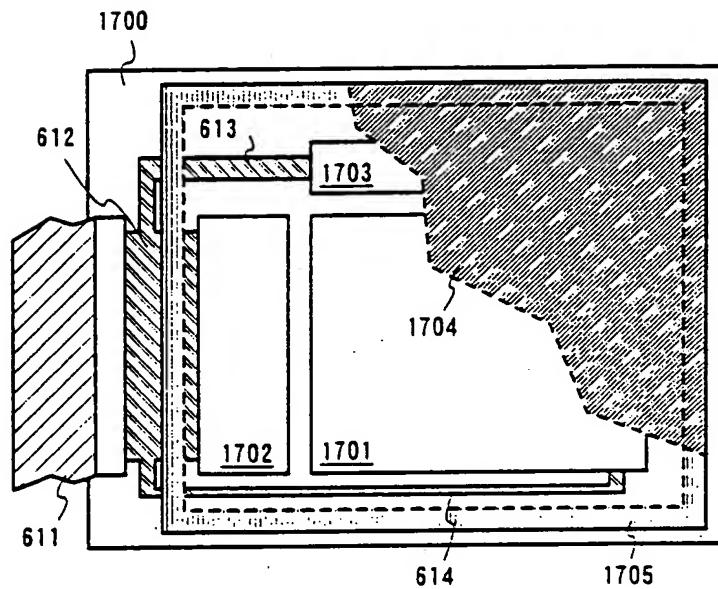


Fig.17A

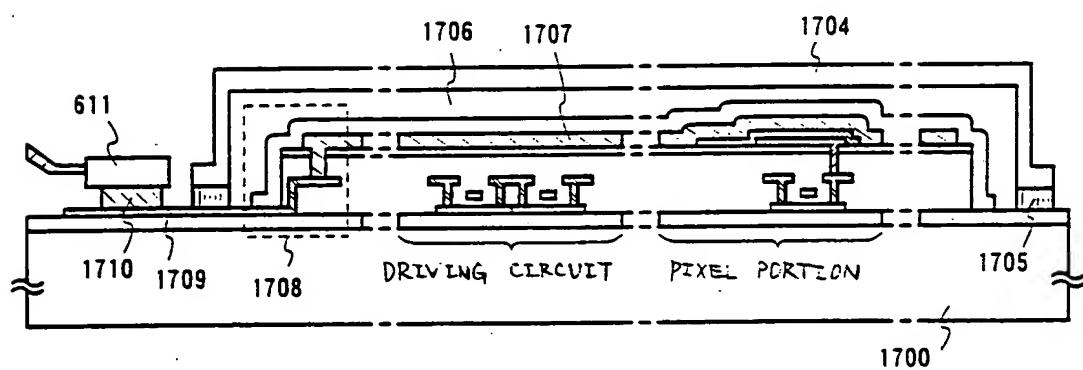


Fig.17B

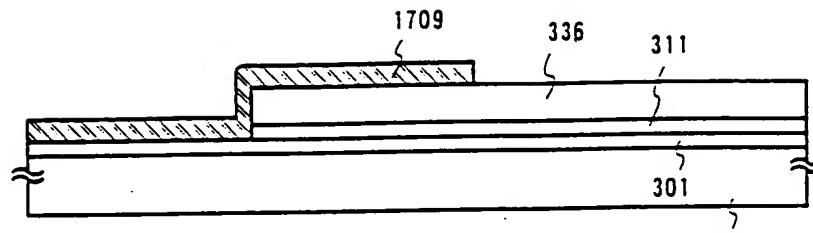


Fig. 18A

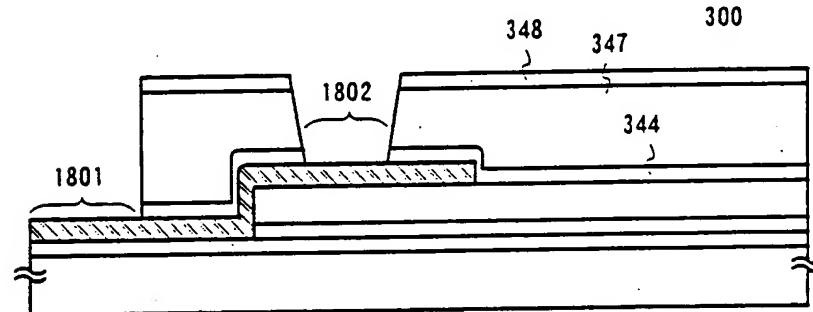


Fig. 18B

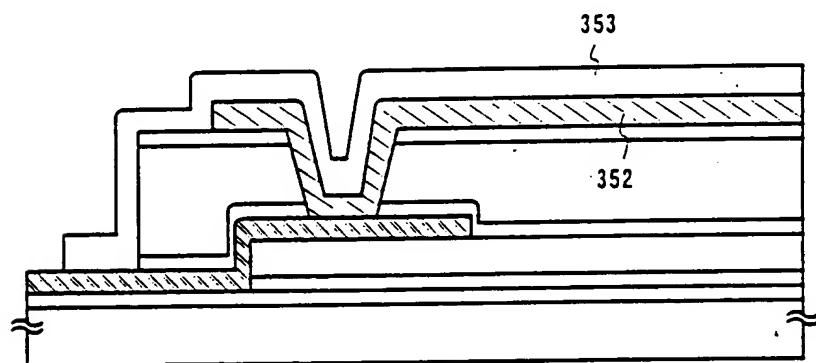


Fig. 18C

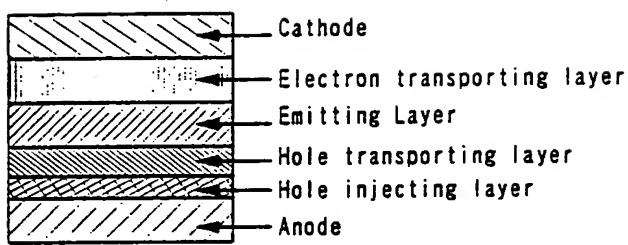


Fig.19

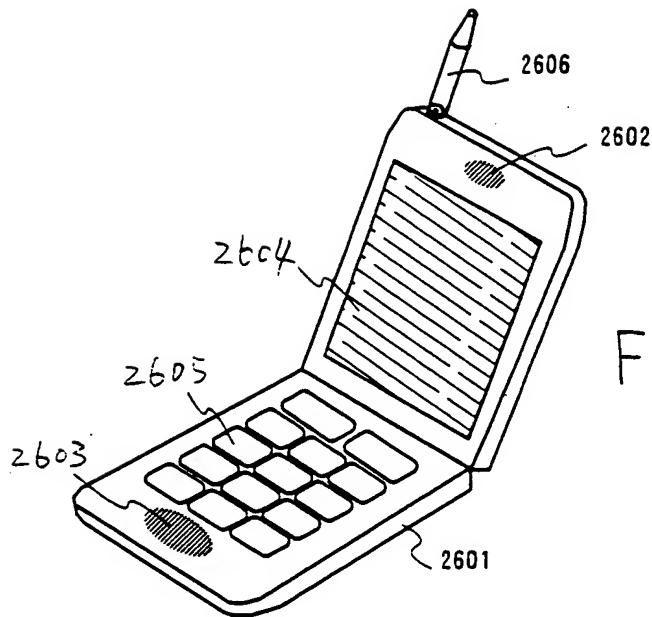


Fig. 20A

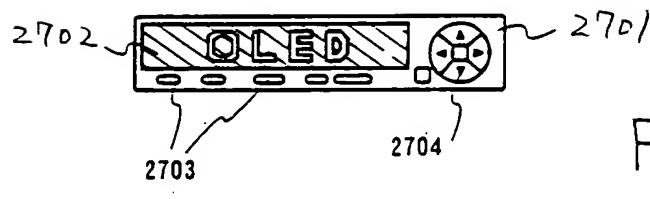


Fig. 20B

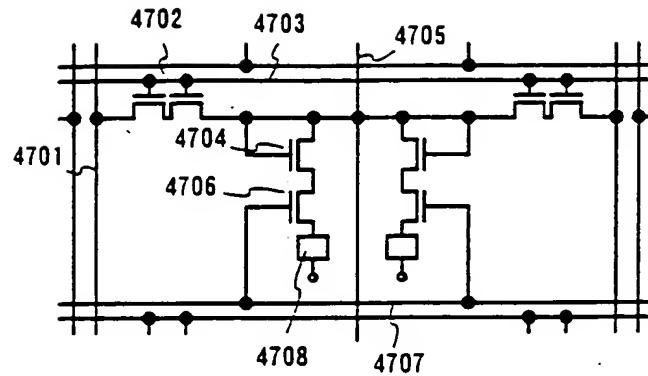


Fig. 21A

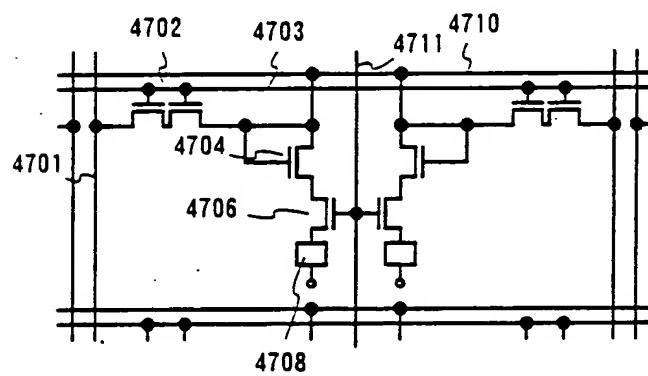


Fig. 21B

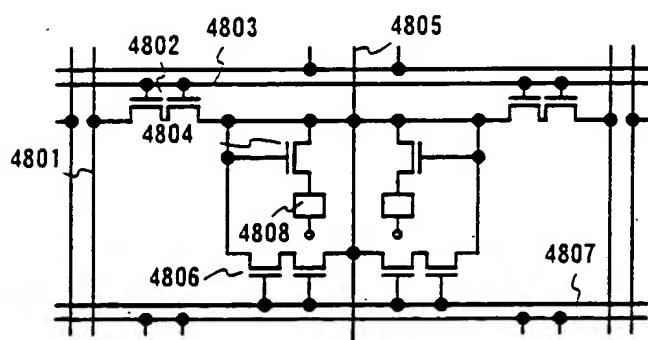


Fig. 22A

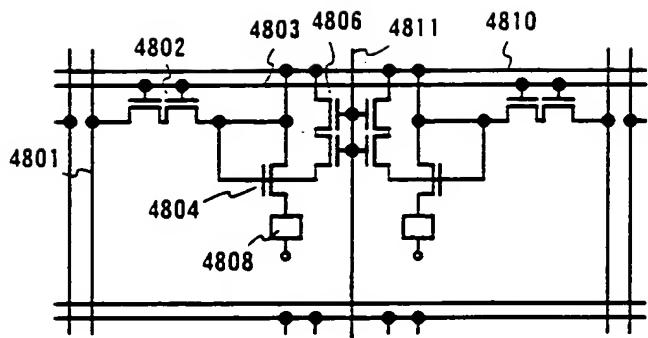


Fig. 22B

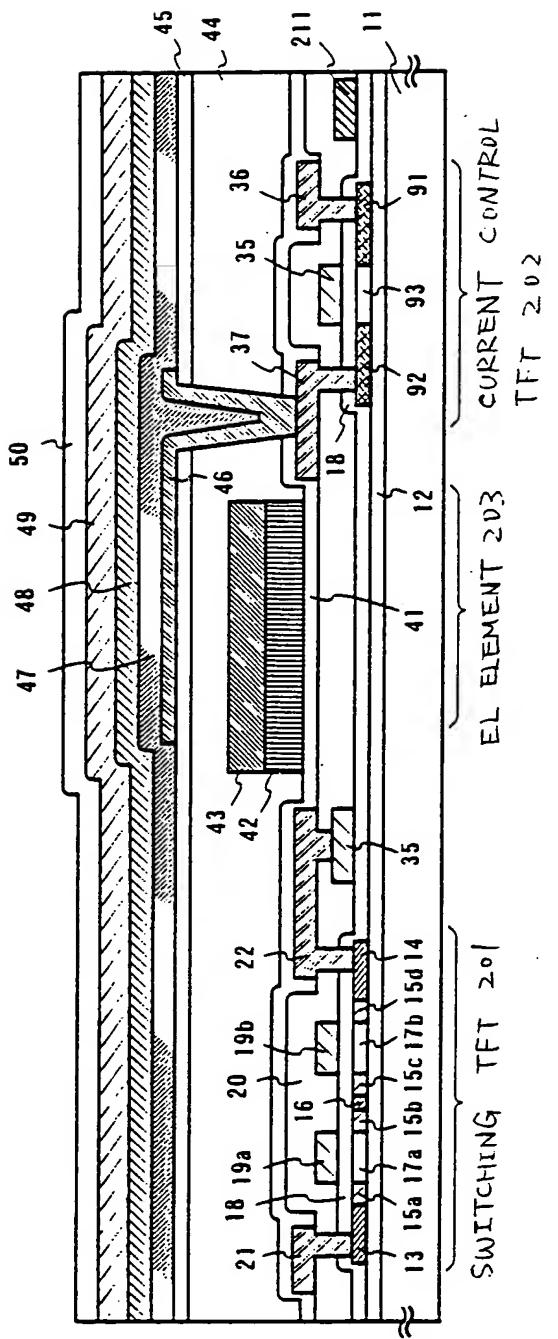


Fig. 23